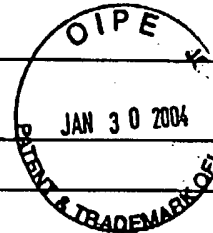


INFORMATION DISCLOSURE CITATION

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Applicant		Oscar David LABRAÑA VALDIVIA et al.	
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U.S. PATENT DOCUMENTS						
Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
	5,204,082	04/20/1993	Schendel			
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
	Koichi; " APPARATUS FOR PRODUCING HIGH-PURITY SULFUR DIOXIDE"; Patent Abstracts of Japan, of JP 09-309707, December 2, 1997
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Examiner	Date Considered 7.8.2004
<p>*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>	
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